

## Transaction Information

Tool ID	SPT03
Tool Status	Running Wafers
Location	East Fishkill, USA
Wafer Size	300 mm
Fab Section	R&D
Tool Available Date	2025-06-30

## General Product Information

Vendor Supplier	Nexx Systems
Model	TEL NEXX APOLLO HP PVD SYSTEM SPT03
Vintage	2012
Serial No	379
Asset Description	TEL NEXX APOLLO HP PVD SYSTEM SPT03
Software Version	Standard
CIM	SECS GEM
Process	PVD Sputter 3D

## Hardware Configuration (Fab)

System Type	Description	Quantity	Status
Handler System	Standard		OK
Others			

## Hardware Configuration (Subfab / Auxilliary Units)

Description	Quantity	Status
NONE		

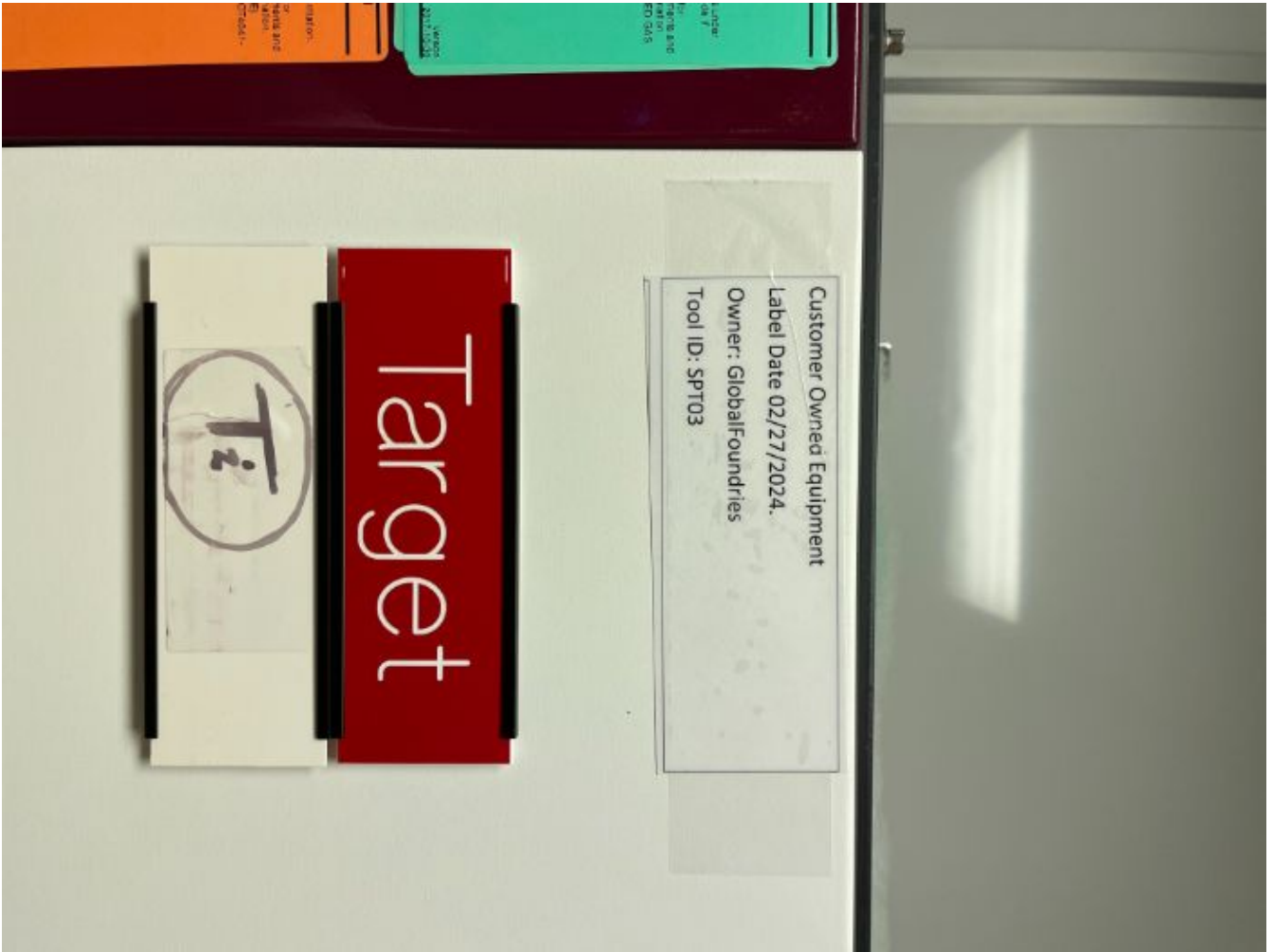
## Missing/Faulty Parts / Accesories List

Description	Quantity
NONE	

# Tool Pictures

General

Main tool



General

Main tool



Manufacture Serial

Serial Plate

# NEXX Systems, Inc.

900 Middlesex Turnpike, Bld. 6  
Billerica, MA USA 01821-3929  
978-932-2000

Model No. Apollo HP  
Part No. K11214066  
Serial No. 379

US Patent Nos. 6,217,272; 6,328,858  
6,682,288; 6,530,733; 6,821,912

Facilities Drawing No. K96208178

208VAC, 3 Ph, 5W, 50/60Hz, 150 amps

Single Largest Load 80A

Main C/B AIC 25000

Process Gas Max:

House N2 Max:

Compressor Air Max:

Water Max

House Loop 1:

House Loop 2:

Comp. Cooling:

DI Loop:

CE Certified

25psi - 1.72 BAR  
60psi - 4.13 BAR  
100psi - 6.9 BAR

75psi - 5.17 BAR  
75psi - 5.17 BAR  
100psi - 6.9 BAR  
60psi - 4.13 BAR

DRAIN

HOUSE WATER-1  
RETURN

ON

## Additional Configuration Files